

SECTION 2. FORMS PTO/SB/08A and 08B (formerly Form PTO-1449)**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: Nunan et al. Attorney Docket: 2550/193
Serial No: Not yet assigned Art Group Unit: Not yet assigned
Date Filed: March 2, 2004 Examiner Name: Not yet assigned
Invention: Single Crystal Silicon Sensor With Additional Layer And Method Of Producing
The Same

**LIST OF PATENTS AND PUBLICATIONS FOR
APPLICANT'S INFORMATION DISCLOSURE STATEMENT**

U.S. PATENT DOCUMENTS					
Examiner Initials	Reference Number	Document Number	Issue Date	Inventor	Class/Subclass
	AA	US 5,939,633	08/17/1999	Judy	73/514.32
	AB	US 6,505,511 B1	01/14/2003	Geen et al.	73/504.12
	AC	US 5,569,621	10/29/1996	Yallup et al.	437/62
	AD	US 6,465,280	10/15/2002	Martin et al.	438/125

OTHER DOCUMENTS			
Examiner Initials	Reference Number	Author	Title of Article, Title of Journal, Volume Number, Page Numbers, Date
	AE	P.-C. Hsu et al.	A High Sensitivity Polysilicon Diaphragm Condensor Microphone, 1998 MEMS Conference, Pgs. 1-6, Jan. 25-29, 1998.

Examiner Signature: _____

Date Considered: _____

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation *if not* in conformance and not considered. Include copy of this form with next communication to applicant.